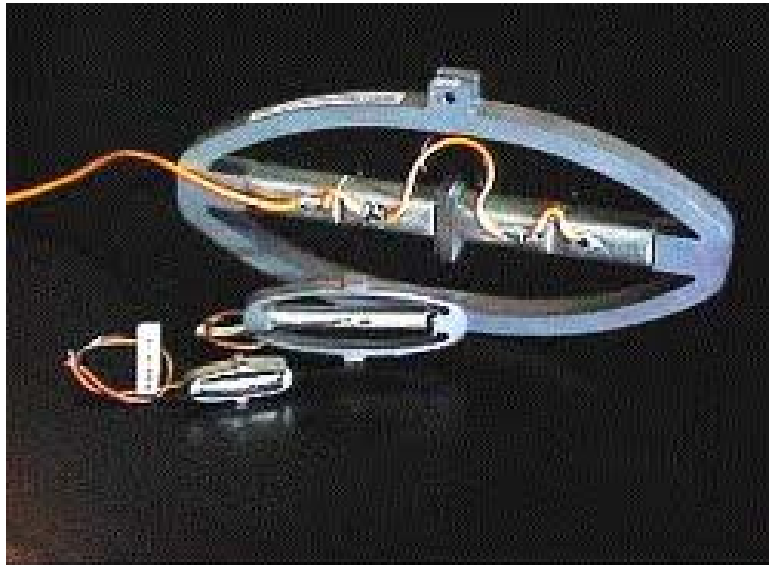
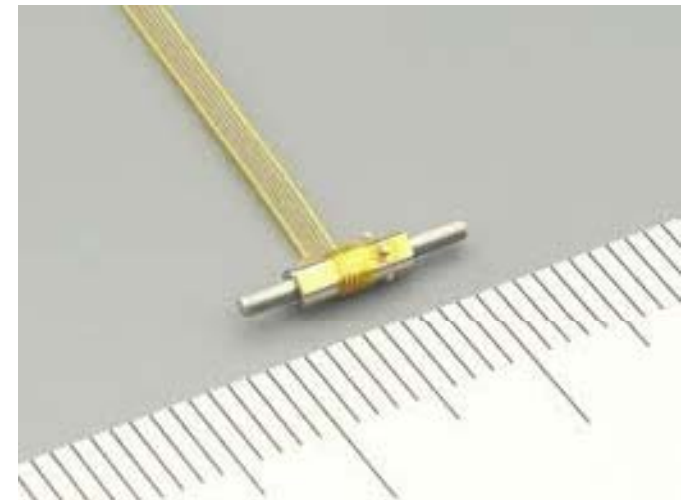


# Actuators & Sensors based on HBLS Smart Materials – Device Design



APA230L, APA150M, APA100S

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# **Topics Covered in the Last Lecture**

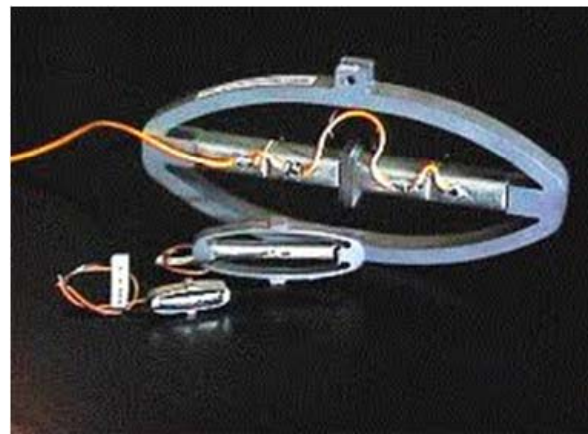
- **HBLS Smart Actuators**
- **Multilayered Piezoelectric Materials**
- **Design Issues**
- **Advanced Devices**

# **This lecture will cover**

- **Piezoelectric Inchworm Devices**
- **Piezoelectric Fuel Injectors**
- **Ultrasonic Motors**

# Two Smart actuators

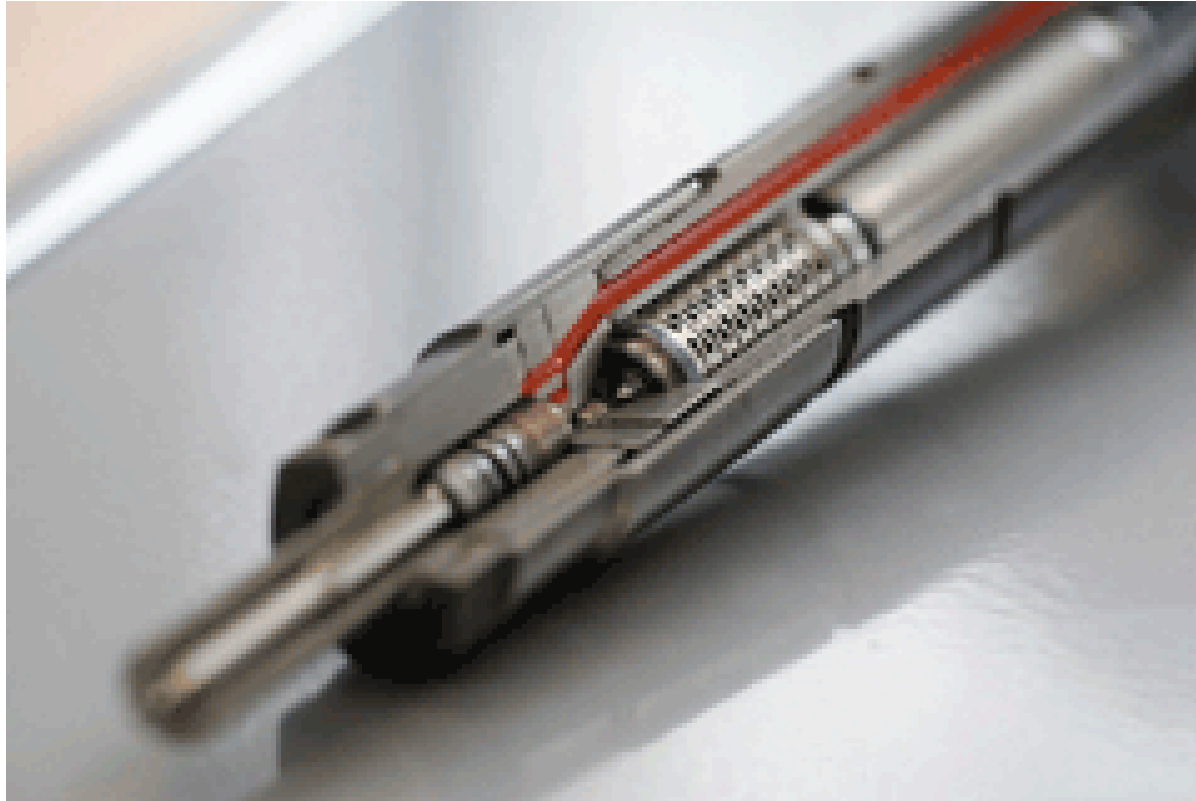
- Thin Disk Buzzer
- Amplified Piezo Actuator



APA230L, APA150M, APA100S

# Introduction

- Current trend in Automotive Electronics is to use actuators for functions which require faster, more powerful and highly precise motion.
- Initiated application of Piezoelectric Actuators and Rheological Fluids for the control of Fuel Injection and motion control.
- Simple Unimorph/Bimorph/Disks are not popular in the industrial scale due to lack of efficiency, displacement and safety.



**Cut-out of a Piezoelectric Fuel Injector from EPCOS**

# Comparison of Different Actuators

Type	Device	Accuracy	Response
Pneumatic	Motor	Degrees	10 secs
Hydraulic	Motor	Degrees	1 sec
Electro-magnet	Stepper	10 $\mu\text{m}$	0.1 sec
Piezoelectric	Actuator	0.01 $\mu\text{m}$	0.0001 sec
Magnetostrictive	Actuator	0.01 $\mu\text{m}$	0.0001 sec
Piezoelectric	Ultrasonic	minutes	0.001 sec

# How can we Maximize the Displacement?

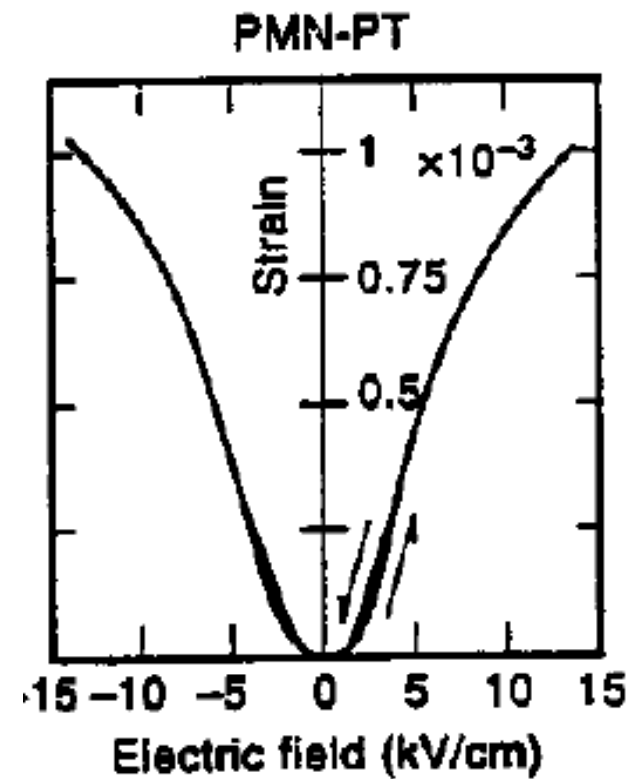
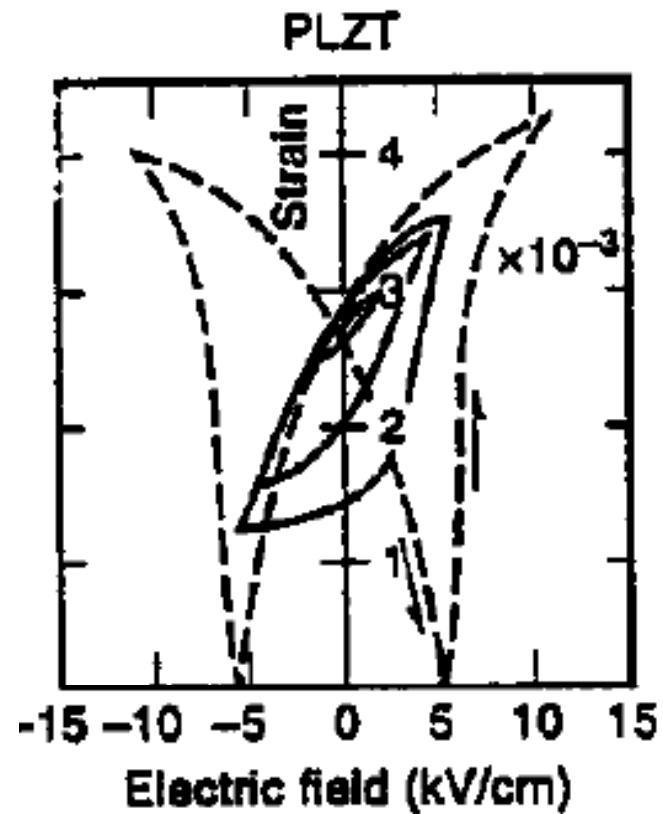
Consider a multilayered piezoelectric stack of length  $l$  and number of layers  $n$ , which is subjected to a voltage  $V$ .

Neglecting elastic deformation, total displacement available from a ' $n$ ' layered stack will be:

$$\Delta = (l \times d \times V / (l/n)) = d \times V \times n$$

Total displacement is directly proportional to the number of layers  $n$ !





A Piezo and an Electrostrictor [Uchino, 2003]

# Even more for Electrostrictors

Consider a multilayered electrostrictive stack of length  $l$  and number of layers  $n$ , which is subjected to a voltage  $V$ .

Neglecting elastic deformation, total displacement available from a ' $n$ ' layered strictor will be:

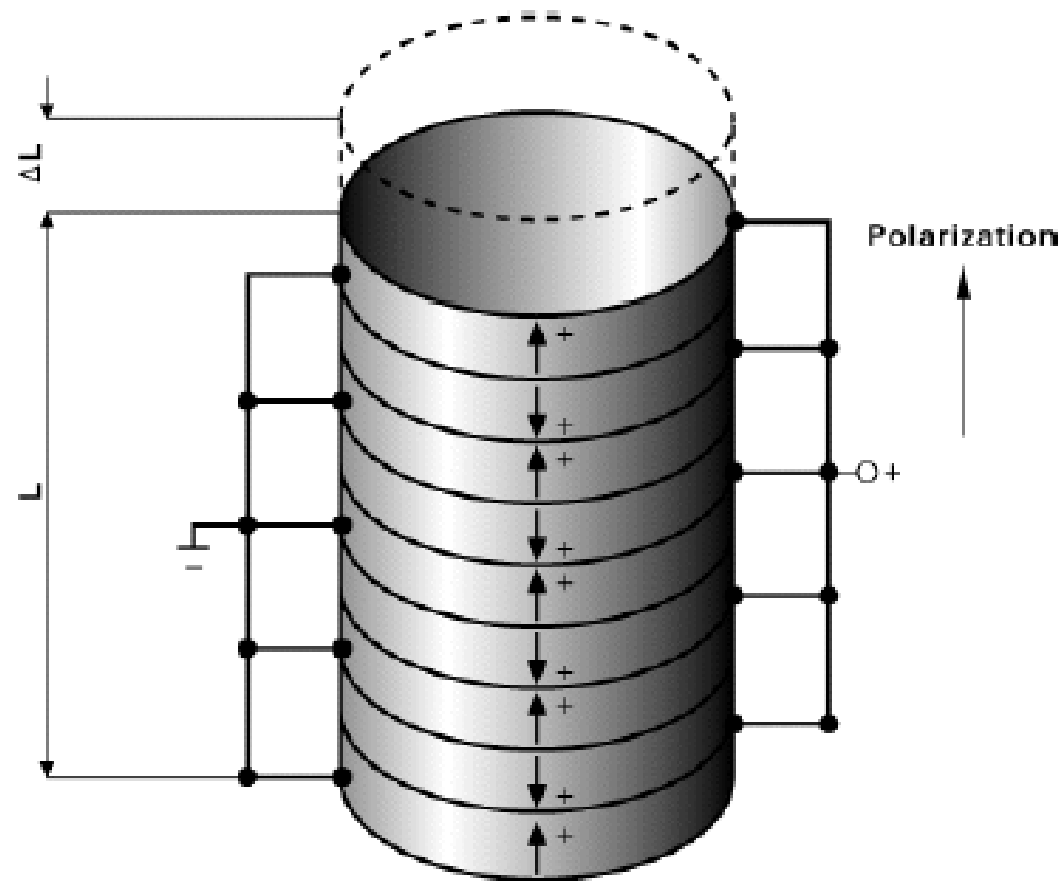
$$\Delta = [ l \times d \times (V / (l/n))^2 ] = (d/l) \times V^2 \times n^2$$

Total displacement is directly proportional to the number of layers  $n^2$  !

# Multilayer Actuators

- Typical layer thickness is about 50 $\mu\text{m}$
- Typical strain available 0.1%
- Hence, for a 100 mm stack actuator with 2000 piezo-electric layers and an applied voltage of about 100V, the displacement will be:  $10 \times 10^{-9} \times 100 \times 2000 = 200 \mu\text{m}$
- Blocking force = 100 kgf
- Lifetime =  $10^{11}$  cycles

# A Typical Multilayer Configuration



# Other important properties

- The resonating frequency of a fixed-free multilayer actuator is given by:

$$f_n = \frac{1}{2l \sqrt{\rho S_{33}^D}}$$

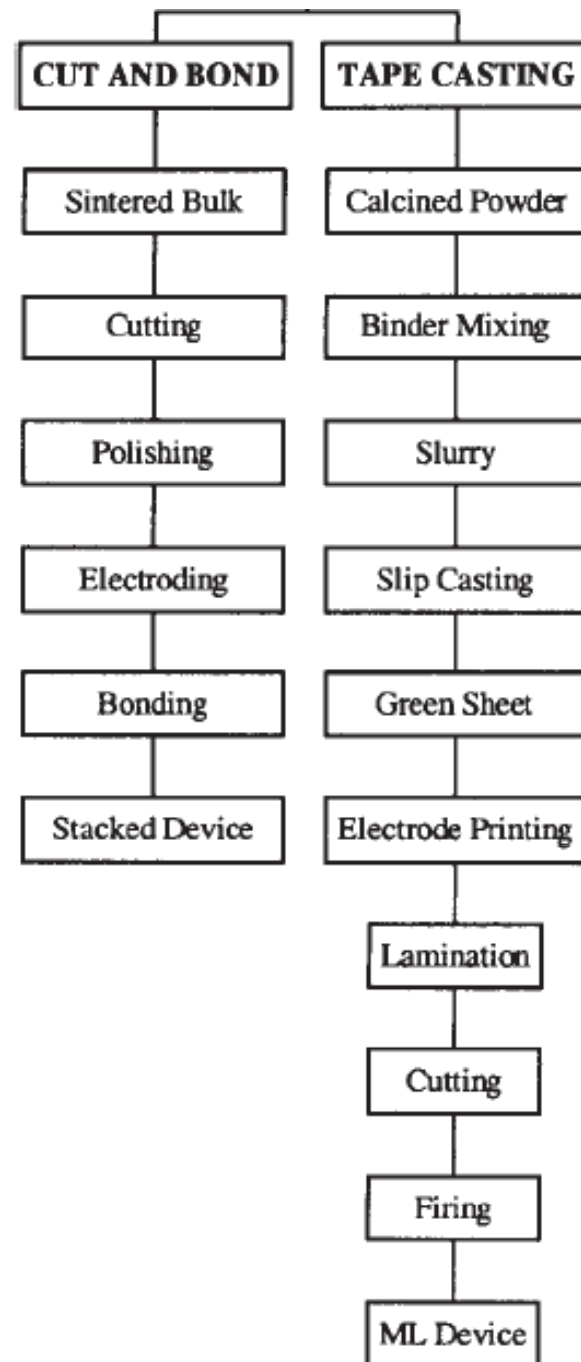
- Where,  $\rho$  is the density and  $S_{33}$  denotes the compliance modulus
- For example, one 1 cm sample will have resonating frequency about 100 kHz.

# Advantages of Multilayered Piezoelectric Actuators

- Requires less voltage
- Produces larger deformation/displacement
- Safer to use
- High Life Cycle
- Lighter and More Compact
- Concurrent engineering – advantages from the development of multi-layered capacitors

# How multilayers are developed?

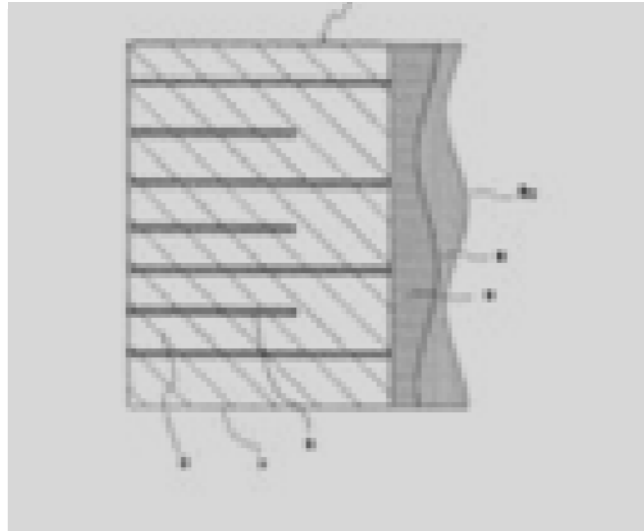
- Two common techniques – Cut and Bond and Tape-Casting
- In cut and bond technique PZT wafers are cut (typical thickness 0.2mm) and bond with intermittent metal foils. Major draw back is that this is a labor intensive process.
- In tape-casting method, ceramic green sheets are printed with electrodes and cofired. There are various ways of electrically connecting such layers.



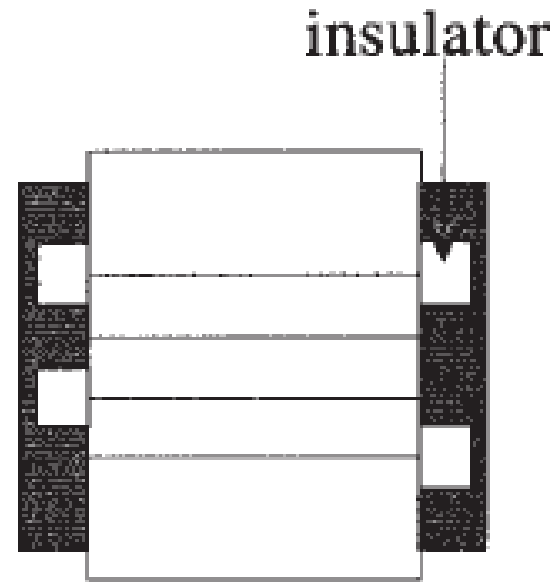
**Reference:**  
J. Pritchard, C. R. Bowen,  
and F. Lowrie, 2000



# Various electrode configurations

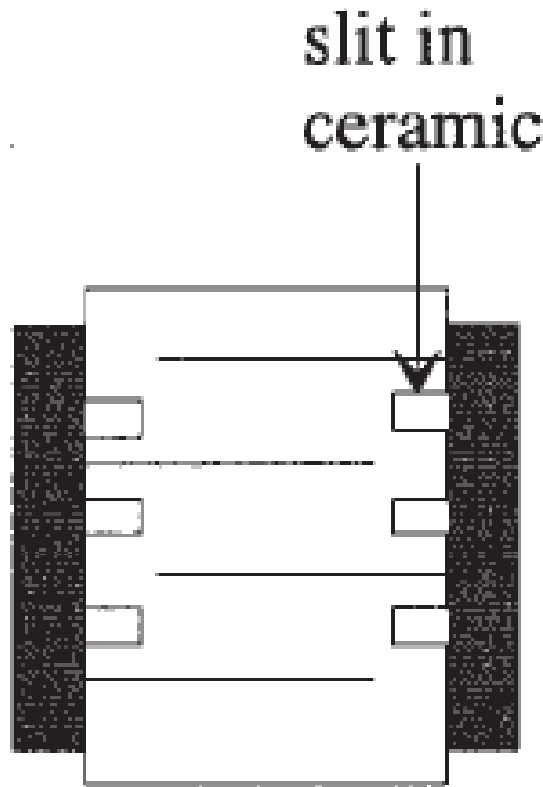


**Interdigital  
Configuration**

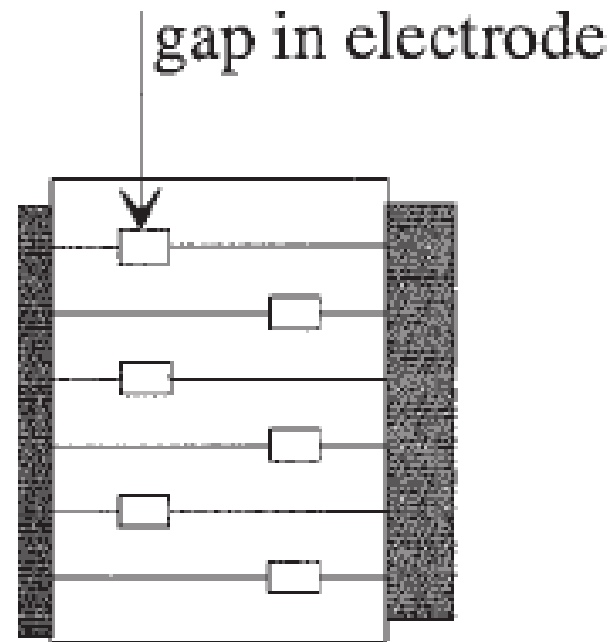


**Plate Through  
Configuration**

# Some more configurations



**Interdigital  
configuration with slit**



**Electrode with  
Gap**

# Design Issues: Electrode Configuration

- Interdigital Configuration is most common and best suitable for mass production. However, due to non-uniform electric field present towards the edges – stress concentration can occur which may lead to failure.
- All other configurations are developed to make the electric field more uniform and hence reduce the stress concentration.

# Design Issues: Inactive Area

- Limited Strain is developed at the edge of the inter-digitated pattern

$$d_{31_{eff}} = \frac{d_{31_{bulk}}}{[1 + \frac{S_e t_e}{S t}]}$$

- Where,  $d_{31_{eff}}$  is the effective coupling constant,  $S$  and  $t$  are the compliance modulus and thickness of piezo while the ones with e-subscript denote that of electrode.

# Design Issues: Delamination

- Delamination can occur between the electrodes and the piezo layers due to binder burn-out, inadequate adhesion between the electrode and the ceramics and thermal expansion mismatch during sintering.
- Solution:
  - Control of Organic Binder
  - Decreasing the Metal Powder Surface Area

# Design Issues: Effect of Composition

- Increase in Grain size increases piezoelectric effect but reduces the fracture toughness, also increases hysteresis and dielectric loss
- For electrodes – Ag-Pd alloy or Copper-Nickel Alloy are better as they have less thermal mismatch.

# Design Issues: Heat Generation

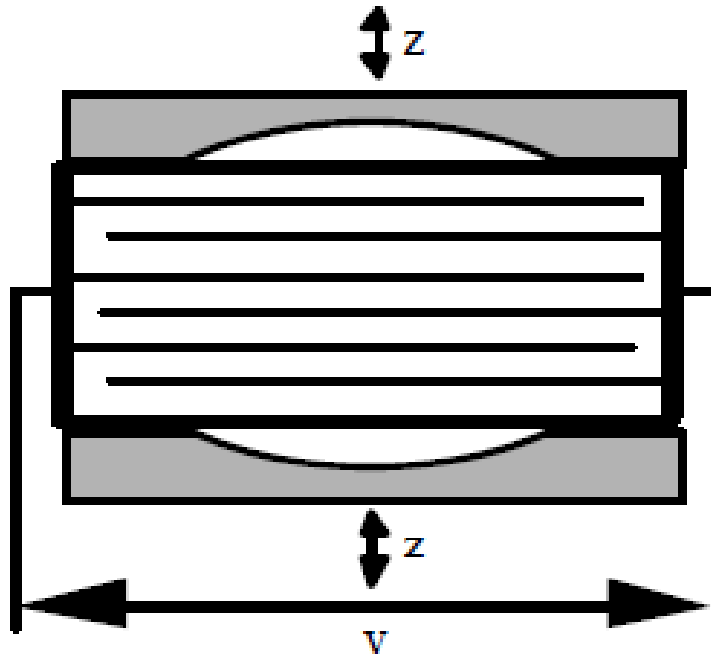
- Heat Generation during operation of such actuator could be expressed as:

$$\Delta T = \frac{U f v_{actuator}}{k(T) A}$$

- $\Delta T$  – change in temperature,  $U$  dielectric loss per driving cycle per volume fraction,  $f$  – driving frequency,  $v$  – actuator volume,  $k$ - conduction coefficient and  $A$  – CS area

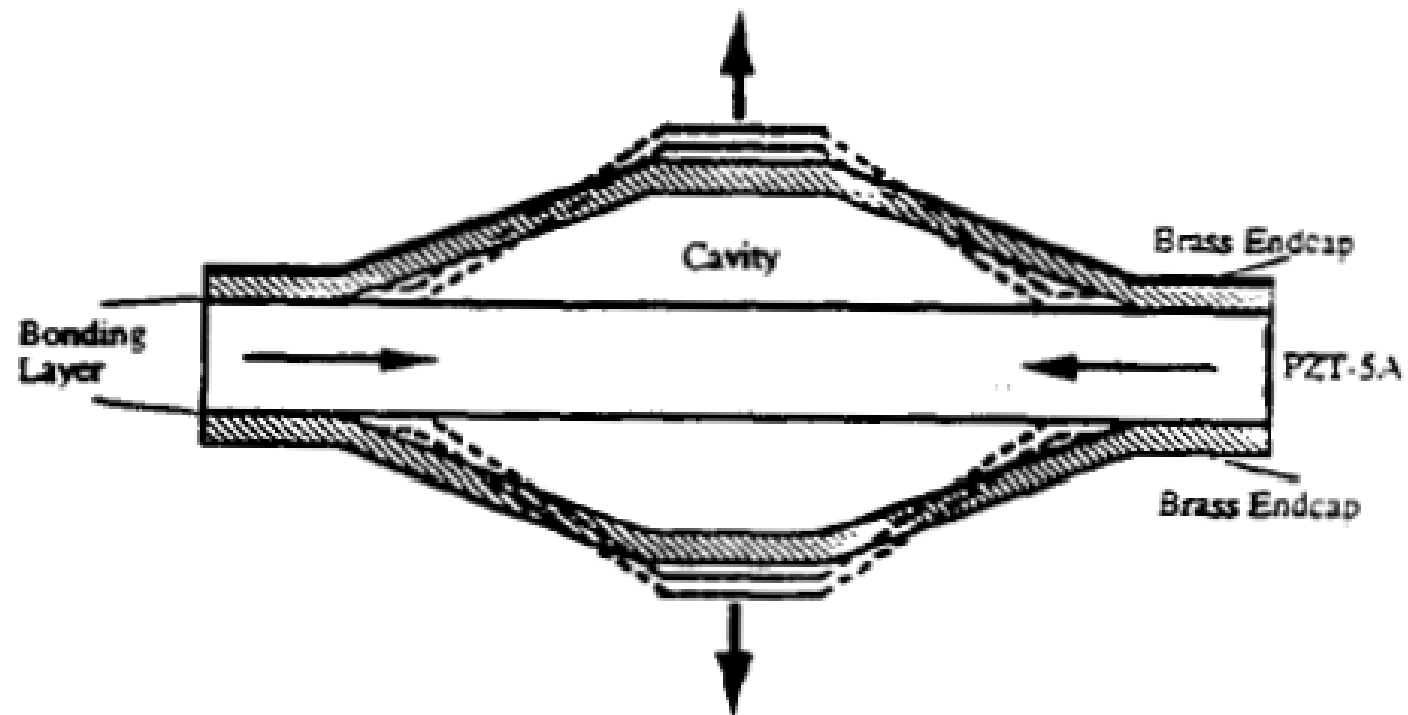
# Further Amplification?

Mooney





# Cymbals



# A Comparison of Actuators

Device	Driving Voltage (V)	Displacement ( $\mu\text{m}$ )	Force (N)	Cost
MLA	100	10	900	High
Bimorph	100	35	1	Low
Rainbow	450	20	3	Medium
Cymbal	100	40	15	Low
Moonie	100	20	3	Medium

# Special reference for this lecture

- Micro-mechatronics by Uchino & Giniewicz, Marcel, Dekker
- Kato, Fine Ceramics Technology
- Pritchard, Bowen, Lowrie; Multilayer Actuators: A Review, British Ceramic Transactions, 2001

**Acknowledgement: Mr. G. Tripathi of the SMSS Lab for the experiment**